

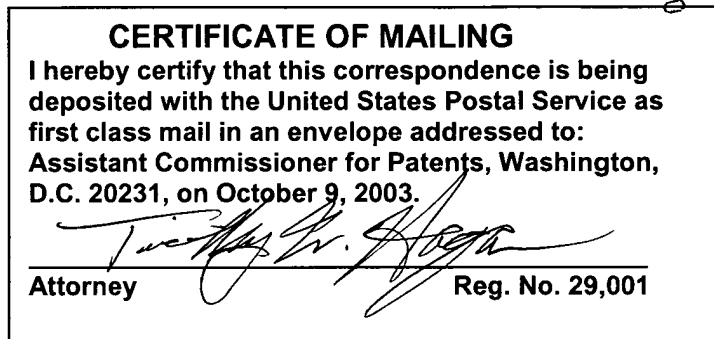
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Applicant : Reza Alani
Serial No. : 09/874,766
Filed : June 5, 2001
Title : **ION BEAM MILLING SYSTEM AND METHOD FOR
ELECTRON MICROSCOPY SPECIMEN PREPARATION**
Docket : GAT 0074 PA
Examiner : H. Tran
Art Unit : 2861
Conf. No. : 5288

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:



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AMENDMENT

This paper is being filed in response to the Office Action mailed July 10, 2003. Reconsideration and reexamination are respectfully requested in light of the amendments and remarks below. This amendment uses the Revised Amendment Practice, 37 CFR §1.121, effective July 30, 2003. The entire set of presently pending claims has been reproduced below in the approved revised amendment format. Amendments relating to the specification, claims, and/or drawings begin on separate pages of this paper. Any amendments to the specification and drawings have also been presented in the revised format. No separate marked-up copy of the amended specification and/or claims has been provided.

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